

PATENT ASSIGNMENT COVER SHEET

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 Stylesheet Version v1.2

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SUBMISSION TYPE:	NEW ASSIGNMENT	
NATURE OF CONVEYANCE:	ASSIGNMENT	
CONVEYING PARTY DATA		
	Name	Execution Date
	AMPHENOL CORPORATION	12/18/2013
RECEIVING PARTY DATA		
Name:	GE THERMOMETRICS, INC.	
Street Address:	967 WINDFALL ROAD	
City:	SAINT MARYS	
State/Country:	PENNSYLVANIA	
Postal Code:	15857-3397	
PROPERTY NUMBERS Total: 2		
Property Type	Number	
Patent Number:	8569851	
Patent Number:	8140146	
CORRESPONDENCE DATA		
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Address Line 1:	600 NEW HAMPSHIRE AVENUE, NW	
Address Line 4:	WASHINGTON, D.C. 20037	
ATTORNEY DOCKET NUMBER:	143210.01348	
NAME OF SUBMITTER:	PETER S. WEISSMAN	
SIGNATURE:	/PETER S. WEISSMAN/	
DATE SIGNED:	08/07/2014	
Total Attachments: 18 source=Assignment#page1.tif source=Assignment#page2.tif source=Assignment#page3.tif source=Assignment#page4.tif source=Assignment#page5.tif source=Assignment#page6.tif		

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ASSIGNMENT

WHEREAS, Amphenol Corporation, a corporation organized and existing under the laws of the State of Delaware with an address at 358 Hall Avenue, Wallingford, CT 06492 ("ASSIGNOR") was the owner of the patents and patent applications set forth on the accompanying Schedule A hereto, and all inventions and embodiments associated therewith ("the Assigned Intellectual Property");

WHEREAS, on or about December 18, 2013, Assignor sold and assigned to GE Thermometrics, Inc., a Pennsylvania corporation and having a principal address at 967 Windfall Road, Saint Marys, PA 15857-3397 ("ASSIGNEE") the Assigned Intellectual Property, as set forth in the Contribution Agreement dated December 18, 2013, by and between Assignor and Assignee (the "Contribution Agreement");

WHEREAS, the parties hereto are desirous of executing a written assignment suitable for recordation with the United States Patent and Trademark Office;

WHEREAS, this Assignment is made pursuant to and in confirmation of the assignment of patent rights as set forth in the Contribution Agreement;

WHEREAS, Assignee changed its name to Amphenol Thermometrics, Inc. on December 19, 2013; and

WHEREAS, Assignor desires to transfer and assign to Assignee, and Assignee desires to accept the transfer and assignment of all of Assignor's right, title and interest in and to the patent applications set forth in Schedule A attached hereto and made a part hereof, and in and to any Letters Patent or Patents, United States or foreign, to be obtained therefor and thereon, the inventions disclosed therein, and all embodiments owned by Assignor in the United States and worldwide, (the "Assigned Patents and Applications").

NOW, THEREFORE, effective as of December 18, 2013 ("Effective Date"), for valuable consideration, and for the consideration set forth in the Contribution Agreement and for other good and valuable consideration, the receipt and sufficiency of which is hereby acknowledged, the Assignor agrees as follows:

1. Assignor hereby irrevocably grants, sells, assigns, transfers, conveys and delivers, free of all encumbrances, to, and as applicable confirms the irrevocable sale, assignment, transfer, conveyance and delivery, free of all encumbrances, to Assignee, and Assignee agrees to accept, all of Assignor's rights, title and interest in and to the Assigned Patents and Applications, *nunc pro tunc* as of the Effective Date, including:

a. all original, reissued, and re-examined letters patents, and renewals and extensions thereof, that originate therefrom in the United States and in foreign countries; and

b. all rights to apply, all rights of priority, all continuation, divisional and continuation-in-part that may be filed therefor in the United States and in foreign countries; and

c. all original, reissued, and re-examined letters patents, and renewals and extensions thereof, that may issue from said continuation, divisional, continuation-in-part and substitute applications; and

d. all present and future causes of action, the right to enforce any and all rights in the Assigned Patents and Applications, the invention disclosed therein, any continuation, divisional, continuation-in-part; substitute patent application, reissued and/or reexamined letters patent, through either legal or administrative proceedings for past and future damages of any sort; the rights to all income derived from the Assigned Patents and Applications and/or the inventions disclosed therein, including the right to all unpaid royalties with respect to the use of the Assigned Patents and Applications and/or the inventions disclosed therein; and any and all interests, claims, and rights for damages, royalties, profits, settlements, and other awards by reason of any past, present or future infringement, and all other related causes of action, and the right to sue therefor, for Assignee's own use and behalf and for the use and behalf of its Affiliates, successors and assigns or other legal representatives.

2. The Assigned Patents and Applications and the inventions disclosed therein are to be held and enjoyed by Assignee, its successors and assigns, as fully and entirely as the same would have been held and enjoyed by Assignor if this Assignment had not been made.

3. Assignor hereby authorizes the United States Patent and Trademark Office and any other governmental agencies having jurisdiction over the Assigned Patents and Applications to identify Assignee as the owner of all letters patents issuing from any applications pending related to the Assigned Patents and Applications. Assignor further hereby authorizes the United States Patent and Trademark Office and any patent office in any and all foreign countries to issue any and all patents related to the Assigned Patents and Applications, including any and all Certificates of Correction, to Assignee as the assignee of Assignor's entire right, title and interest in and to the same, for the sole use and behalf of Assignee, its successors, assigns, and/ or legal representatives, from now through the full end of the term for which any additional patents may be granted.

IN WITNESS WHEREOF, the parties have caused this Assignment to be executed by its duly authorized officer.

ASSIGNOR:
AMPHENOL CORPORATION:

Date: JANUARY 14, 2014

By: Edward C. Wetmore
Edward C. Wetmore, Esq.
Secretary and General Counsel

ASSIGNEE:
GE THERMOMETRICS, INC.:

Date: JANUARY 14, 2014

By: Edward C. Wetmore
Edward C. Wetmore, Esq.
Secretary

SCHEDULE A

Patent Registrations

Docket Number	Application Number	Publication Number	Patent Number	Filing Country	Title
126153 -1	10/250084		6938482	US	Humidity sensor element containing polyphenylsulfone
130247 -1	96906267.8		69613213.3	DE	Temperature sensor probe
130247 -2	96/906267		807245	GB	Temperature sensor probe
134166 -1	10/706767		7053425	US	Gas sensor device
134166 -5	2006-539502		5290521	JP	Gas sensor device
135340 -1	09/255304		6076396	US	Moisture sensing probe
139641 -1	10/799053		7114397	US	Microelectromechanical system pressure sensor and method for making and using
139641 -3	11/495317		7296476	US	Microelectromechanical system pressure sensor and method for making and using
139641 -4	11/495318		7305889	US	Microelectromechanical system pressure sensor and method for making and using
140272 -1	10/802339		7128467	US	Thermistor probe assembly and method for positioning and moisture proofing thermistor probe assembly
140338 -1	10/839095		7253615	US	Microelectromechanical system sensor and method for using
140655 -1	10/605472		6927482	US	Surface mount package and method for forming multi-chip microsensor device
140655 -3	11/052290		7157312	US	Surface mount package and method for forming multi-chip microsensor device
140655	04785002.9		1671091	EP	Surface mount package and method for forming multi-chip microsensor device
141182 -1	08/877415		6076965	US	Monocrystal of nickel-cobalt-manganese oxide having a cubic spinel structure, method of growth and sensor formed therefrom
145204 -1	10/813101		7138901	US	Temperature measuring device and system and method incorporating the same
148398 -1	10/909062		7116036	US	Energy harvesting system, apparatus and method
148468 -1	10/945399		7560788	US	Microelectromechanical system pressure sensor and method for making and using
148468 -2	11/677629		7563692	US	Microelectromechanical system pressure sensor and method for making and using

Docket Number	Application Number	Publication Number	Patent Number	Filing Country	Title
148474 -1	10/938247		7101789	US	Method of wet etching vias and articles formed thereby
148474 -2	11/337249		7365437	US	Method of wet etching vias and articles formed thereby
151150 -3	2005-028526		4871513	JP	Micromechanical device with thinned cantilever structure and related methods
151150 -4	11/322852		7223624	US	Micromechanical device with thinned cantilever structure and related methods
155889 -1	11/023202		7181972	US	Static and dynamic pressure sensor
157961 -1	09/892155		6635020	US	Reusable fluid pressure transducer monitoring apparatus
158261 -1	11/061706		7132757	US	Power control system and method
158261 -2	11/582236		7331803	US	Power control system and method
162240 -1	11/095243		7338640	US	Thermopile-based gas sensor
170595 -6	2008-528091	2009-506323	5342236	JP	Pressure sensors and methods of making the same
170595 -7	20087004343	102008003196 9	10-1296031	KR	Pressure sensors and methods of making the same
170595 -1	11/210309		7622782	US	Pressure sensors and methods of making the same
170595 -10	06802137.7		1920229	FI	Pressure sensors and methods of making the same
170595 -11	06802137.7		1920229	FR	Pressure sensors and methods of making the same
170595 -12	06802137.7		60200602560 1.9	DE	Pressure sensors and methods of making the same
170595 -13	06802137.7		1920229	GB	Pressure sensors and methods of making the same
170595 -14	06802137.7		1920229	IT	Pressure sensors and methods of making the same
170595 -3	200680031097. 6		20068003109 7.6	CN	Pressure sensors and methods of making the same
170595 -4	06802137.7		1920229	EP	Pressure sensors and methods of making the same
170595 -8	200801122.3		139997	SG	Pressure sensors and methods of making the same
170595 -9	06802137.7		1920229	AT	Pressure sensors and methods of making the same
181222 -7	2008-526956		5357542	JP	Mid-infrared resonant cavity light emitting diodes
181222 -1	11/203398		7560736	US	Mid-infrared resonant cavity light emitting diodes
181222 -4	200680038382. 0		20068003839 2.0	CN	Mid-infrared resonant cavity light emitting diodes
213297 -1	11/565202		7582859	US	Infrared sensor calibration system and method
214673 -1	11/648919		7880580	US	Thermistor having doped and undoped layers of material

Docket Number	Application Number	Publication Number	Patent Number	Filing Country	Title
222275 - 5	2007-325419		5041999	JP	Temperature sensor
222275 - 6	2007-0134358		10-1321169	KR	Temperature sensor
222275 -1	11/614243		7312690	US	Temperature sensor
222275 -2	200710300818.5		200710300818.5	CN	Temperature sensor
225622 -3	0822498	2455640	2455640	GB	Gas sensor and method of making
226392 -2	12/205098		8118481	US	Fluid detector
227142 -2	12/202589		7740402	US	Fluid detector
228142 -3	0822499	2455641	2455641	GB	Gas sensor and method of making
231260 -1	12/130539		8140146	US	Catheter tip device and method for manufacturing same
231260 -4	200980121192.9		200980121192.9	CN	Catheter tip device and method for manufacturing same
235977 -1	12/683474		8364427	US	Flow sensor assemblies
238205 - 8	MX/a/2010/014241		307831	MX	Device for measuring fluid properties in caustic environments
238205 -1	12/645972		8002315	US	Device for measuring fluid properties in caustic environments
238472 - 4	2011-195530		5351943	JP	Device for use as dual-sided sensor package
238472 -1	12/879143		8264074	US	Device for use as dual-sided sensor package
240804 -5	2010-291906		5134679	JP	Snap-fit sensor assembly
240804 -1	12/649969		8142073	US	Snap-fit sensor assembly
241065 -6	2012-530882		5352011	JP	Method and system for compensating for variation in attenuation measurements caused by changes in ambient temperature
241065 -7	2012-7010154		10-1280190	KR	Method and system for compensating for variation in attenuation measurements caused by changes in ambient temperature
241065 -1	12/569258		8283930	US	Method and system for compensating for variation in attenuation measurements caused by changes in ambient temperature
241230 -1	12/647660	US2011-0159627	8569092	US	Method for fabricating a microelectromechanical sensor with a piezoresistive type readout
241230 -6	10195522.7		2339357	DE	Method for fabricating a microelectromechanical sensor with a piezoresistive type readout
241230 -7	10195522.7		2339357	GB	Method for fabricating a microelectromechanical sensor with a piezoresistive type readout
241230 -8	10195522.7		2339357	IT	Method for fabricating a microelectromechanical sensor with a piezoresistive type readout
241351 -2	12/818635	0309458	8569851	US	Sensor and method for fabricating the same

Docket Number	Application Number	Publication Number	Patent Number	Filing Country	Title
241351 -1	12/818611		8435821	US	Sensor and method for fabricating the same
241351 -10	2011/0282		86121	IE	Sensor and method for fabricating the same
241351 -5	2011/0281		86120	IE	Sensor and method for fabricating the same
242894 -1	12/968346		7998777	US	Method for fabricating a sensor
245281 -1	12/951330		8261618	US	Device for measuring properties of working fluids
248451 -1	13/106416	US-2012-0285739-A1	8492652	US	Apparatus and method to attach probe to junction box
RD28435 -2	09/681304		6773962	US	Microelectromechanical system device packaging method
RD28435 -3	10/167546		6767764	US	Microelectromechanical system device packaging method

Docket Number	Application Number	Publication Number	Patent Number	Filing Country	Title
130796 -1	09/005766		6073480	US	Humidity sensor with differential thermal detection and method of sensing
130796 -2	08/764180		5792938	US	Humidity sensor with differential thermal detection and method of sensing
135313 -1	08/652867		6316796	US	Single crystal silicon sensor with high aspect ratio and curvilinear structures
135315 -1	08/449140		6084257	US	Single crystal silicon sensor with high aspect ratio and curvilinear structures
135315 -11	8-535885		4477143	JP	Single crystal silicon sensor with high aspect ratio and curvilinear structures and associated method
135315 -12	96916597		829012	AT	Single crystal silicon sensor with high aspect ratio and curvilinear structures and associated method
135315 -13	96916597		829012	BE	Single crystal silicon sensor with high aspect ratio and curvilinear structures and associated method
135315 -14	96916597		829012	CH	Single crystal silicon sensor with high aspect ratio and curvilinear structures and associated method
135315 -15	96916597		829012	DE	Single crystal silicon sensor with high aspect ratio and curvilinear structures and associated method
135315 -16	96916597		829012	DK	Single crystal silicon sensor with high aspect ratio and curvilinear structures and associated method
135315 -17	96916597		829012	ES	Single crystal silicon sensor with high aspect ratio and curvilinear structures and associated method

Docket Number	Application Number	Publication Number	Patent Number	Filing Country	Title
135315 -18	96916597		829012	FI	Single crystal silicon sensor with high aspect ratio and curvilinear structures and associated method
135315 -19	96916597		829012	FR	Single crystal silicon sensor with high aspect ratio and curvilinear structures and associated method
135315 -20	96916597		829012	GB	Single crystal silicon sensor with high aspect ratio and curvilinear structures and associated method
135315 -22	96916597		829012	IE	Single crystal silicon sensor with high aspect ratio and curvilinear structures and associated method
135315 -23	96916597		829012	IT	Single crystal silicon sensor with high aspect ratio and curvilinear structures and associated method
135315 -24	96916597		829012	LU	Single crystal silicon sensor with high aspect ratio and curvilinear structures and associated method
135315 -26	96916597		829012	NL	Single crystal silicon sensor with high aspect ratio and curvilinear structures and associated method
135315 -27	96916597		829012	PT	Single crystal silicon sensor with high aspect ratio and curvilinear structures and associated method
135315 -28	96916597		829012	SE	Single crystal silicon sensor with high aspect ratio and curvilinear structures and associated method
135315 -3	96916597.6		829012	EP	Single crystal silicon sensor with high aspect ratio and curvilinear structures and associated method
135320 -1	08/098182		5461922	US	Pressure sensor isolated within housing having integral diaphragm and method of making same
135324 -1	08/944733		6038928	US	Miniature gauge pressure sensor using silicon fusion bonding and back etching
135324 -2	09/449009		6629465	US	Miniature gauge pressure sensor using silicon fusion bonding and back etching
135324 -6	97910711.7		69729753.5	DE	Silicon at least 5 micron high acute cavity with channel by oxidizing fusion bonding and stop etching
135324 -7	97910711.7		1012552	GB	Silicon at least 5 micron high acute cavity with channel by oxidizing fusion bonding and stop etching
135792 -1	09/326931		6523560	US	Microvalve with pressure equalization
135959 -1	09/815900		6559379	US	Pressure sensor with transducer mounted on a metal base
135959 -2	95/001784			US	Pressure sensor with transducer mounted on a metal base

Docket Number	Application Number	Publication Number	Patent Number	Filing Country	Title
138981 -21	2000-569132		4831446	JP	Proportional micromechanical device
138981 -25	10/024963		6761420	US	Proportional micromechanical device
138981 -26	11/075057		7367359	US	Proportional micromechanical valve
138981 -27	99946703.8		1117937	FR	Proportional micromechanical device
138981 -28	99946703.8		69938602.0	DE	Proportional micromechanical device
138981 -29	99946703.8		1117937	GB	Proportional micromechanical device
140230 -1	10/024957		7011378	US	Proportional micromechanical valve
172936 -10	H6-44		2610101	JP	Uniform reference device that is used together with modular screw-fixed block
172936 -2	93310457.2		605201	EP	Uniform temperature reference block
172936 -3	93310457.2		605201	CH	Uniform temperature reference block
172936 -4	93310457.2		69317749	DE	Uniform temperature reference block
172936 -5	93310457.2		605201	FR	Uniform temperature reference block
172936 -6	93310457.2		605201	GB	Uniform temperature reference block
172936 -7	93310457.2		605201	IT	Uniform temperature reference block
172936 -8	93310457.2		605201	SE	Uniform temperature reference block
172936 -9	2110842		2110841	CA	Uniform Temperature Reference Apparatus for Use with Modular Screw-Terminal Block
172940 -1	08/529356		5741073	US	Uniform temperature reference apparatus for use with modular terminal block
172945 -1	09/922282		6836220	US	Miniaturized self-contained sensors for monitoring and storing data as to temperature and the like at remote areas and removable therefrom for digital reading, and novel method of operating the same
172945 -10	2004-7001715		100840634	KR	Improved miniaturized self-contained sensors for monitoring and storing data
172945 -11	2278360		2278360	RU	Improved miniaturized self-holding sensors for monitoring and storing data
172945 -12	2004/001141		246050	MX	Improved miniaturized self-contained sensors for monitoring and storing data
172945 -13	1274422.3		1423669	AT	Improved miniaturized self-contained sensors for monitoring and storing data
172945 -14	1274422.3		1423669	BE	Improved miniaturized self-contained sensors for monitoring and storing data
172945 -15	1274422.3		1423669	DK	Miniaturized self-contained sensors for monitoring and storing data as to temperature and the like at remote areas and removable therefrom for digital reading, and novel method of operating the same
172945 -16	1274422.3		1423669	FI	Improved miniaturized self-contained sensors for monitoring and storing data
172945 -17	1274422.3		1423669	FR	Improved miniaturized self-contained sensors for monitoring and storing data

Docket Number	Application Number	Publication Number	Patent Number	Filing Country	Title
172945 -18	1274422.3		1423669	DE	Improved miniaturized self-contained sensors for monitoring and storing data
172945 -19	1274422.3		1423669	GB	Improved miniaturized self-contained sensors for monitoring and storing data
172945 -20	1274422.3		1423669	GR	Improved miniaturized self-contained sensors for monitoring and storing data
172945 -21	1274422.3		1423669	IE	Improved miniaturized self-contained sensors for monitoring and storing data
172945 -22	1274422.3		1423669	IT	Improved miniaturized self-contained sensors for monitoring and storing data
172945 -23	1274422.3		1423669	NL	Improved miniaturized self-contained sensors for monitoring and storing data
172945 -24	1274422.3		1423669	PT	Improved miniaturized self-contained sensors for monitoring and storing data
172945 -25	1274422.3		1423669	ES	Improved miniaturized self-contained sensors for monitoring and storing data
172945 -26	1274422.3		1423669	SE	Improved miniaturized self-contained sensors for monitoring and storing data
172945 -27	1274422.3		1423669	CH	Improved miniaturized self-contained sensors for monitoring and storing data
172945 -5	2456109		2456109	CA	Improved miniaturized self-contained sensors for monitoring and storing data
172945 -6	1823685.5		1823685.5	CN	Improved miniaturized self-contained sensors for monitoring and storing data
172945 -9	2003-519364		4191031	JP	Miniaturized self-contained sensors for monitoring and storing data as to temperature and the like at remote areas and removable therefrom for digital reading, and novel method of operating the same
185518 -1	09/751668		6526801	US	Method of compensating for drift in gas sensing equipment
185549 -1	08/077488		5592147	US	False alarm resistant fire detector with improved performance
185549 -2	03107406.0		1055149	HK	False alarm resistant fire detector with improved performance
192974 -1	11/347711		7348538	US	Methods and systems for detecting proximity of an object
192976 -1	11/347712		7407323	US	Methods and systems for determining temperature of an object
233093 -2	12564527		8183975	US	Miniature pressure transducer
238009 -1	12/537039	2011-0032971	8545096	US	Thermal sensor device and method of assembly
185520 -1	09/695267		6255653	US	Diffusion-type NDIR gas analyzer with improved response time due to convection flow
185522 -1	09/613987		6410918	US	Diffusion-type NDIR gas analyzer with improved response time due to convection flow
185522 -2	98953829.3		1027592	EP	Diffusion-type NDIR gas analyzer with improved response time due to convection flow

Docket Number	Application Number	Publication Number	Patent Number	Filing Country	Title
185522 -3	98953829.3		69829688	DE	Diffusion-type NDIR gas analyzer with improved response time due to convection flow
185522 -4	98953829.3		1027592	FR	Diffusion-type NDIR gas analyzer with improved response time due to convection flow
185522 -6	11102/99		753912	AU	Diffusion-type NDIR gas analyzer with improved response time due to convection flow
185524 -1	09/593341		6285290	US	Self-cleaning oven having smoke detector controlling cleaning cycle time
185537 -1	09/842622		6588250	US	Automatic calibration mode for carbon dioxide sensor
185537	02811752.2			CN	Automatic calibration mode for carbon dioxide sensor
185537	1020037014102			KR	Automatic calibration mode for carbon dioxide sensor
185537	2002-585952			JP	Automatic calibration mode for carbon dioxide sensor
185619 -11	93917242.5		634009	FR	Improved diffusion-type gas sample chamber
185619 -12	93917242.5		634009	GB	Improved diffusion-type gas sample chamber
185619 -16	2119127		2119127	CA	Improved diffusion-type gas sample chamber
185619 -5	93917242.5		634009	EP	Improved diffusion-type gas sample chamber
185619 -9	93917242.5		634009	DE	Improved diffusion-type gas sample chamber
185657 -1	08/422507		5650624	US	Passive infrared analysis gas sensor
200753 -10	94925177.1		738405	SE	Self-calibration of a NDIR gas sensor
200753 -11	94925177.1		738405	CH	Self-calibration of a NDIR gas sensor
200753 -2	94925177.1		738405	EP	Self-calibration of a NDIR gas sensor
200753 -3	94925177.1		738405	BE	Self-calibration of a NDIR gas sensor
200753 -4	94925177.1		738405	DK	Self-calibration of a NDIR gas sensor
200753 -5	94925177.1		738405	FR	Self-calibration of a NDIR gas sensor
200753 -6	94925177.1		738405	DE	Self-calibration of a NDIR gas sensor
200753 -7	94925177.1		738405	GB	Self-calibration of a NDIR gas sensor
200753 -8	94925177.1		738405	IE	Self-calibration of a NDIR gas sensor
200753 -9	94925177.1		738405	NL	Self-calibration of a NDIR gas sensor
	08/593253		5767776	US	Fire Detector

Patent Applications

Docket Number	Application Number	Publication Number	Patent Number	Filing Country	Title
264003	29/464779			US	Protimeter
134166 -3	2544939			CA	Gas sensor device
134166 -4	04794773.4	1685394		EP	Gas sensor device
170595 -5	1129/DELNP/2008			IN	Pressure sensors and methods of making the same
170595 -6	2008-528091			JP	Pressure sensors and methods of making the same
181222 -3	2618695			CA	Mid-infrared resonant cavity light emitting diodes
222275 -3	07122489.3	EP1936341		EP	Temperature sensor
222275 -4	2565/DEL/2007			IN	Temperature sensor
225622 -1	11/960781	20090159445		US	Gas sensor and method of making
225622 -2	102008055568	102008055568		DE	Gas sensor and method of making
225622 -4	2008-320385	2009-150884		JP	Gas sensor and method of making
226392 -1	07116481.8	2037234		EP	Fluid detector
227142 -1	07116478.4	2037233		EP	Fluid detector
228142 -1	11/960769	20090159447		US	Gas sensor and method of making
228142 -2	102008055571	102008055571		DE	Gas sensor and method of making
228142 -4	2008-321832	2009-150889		JP	Gas sensor and method of making
231260 -3	PI0909585-3			BR	Catheter tip device and method for manufacturing same
231260 -5	09755525.4	2296538		EP	Catheter tip device and method for manufacturing same
231260 -6	2011-511672			JP	Catheter tip device and method for manufacturing same
235977 -2	13/722096	20130116940		US	Flow sensor assemblies
238205 -2	PI1005778-1			BR	Device for measuring fluid properties in caustic environments
238205 -3	2725710			CA	Device for measuring fluid properties in caustic environments
238205 -4	201010620955.9	CN102109450		CN	Device for measuring fluid properties in caustic environments
238205 -5	10195750.4	EP2339311		EP	Device for measuring fluid properties in caustic environments
238205 -6	2010-283947			JP	Device for measuring fluid properties in caustic environments
238205 -7	2010-0132635			KR	Device for measuring fluid properties in caustic environments
238472 -2	201110278773.2	102435226		CN	Device for use as dual-sided sensor package
238472 -3	102011053434.2	102011053434		DE	Device for use as dual-sided sensor package

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238472 - 5	201106450-8	179365		SG	Device for use as dual-sided sensor package
239156 -1	12/539388	20110039137		US	Battery cell with integrated sensing platform
239156 -3	201080046900.X			CN	Battery cell with integrated sensing platform
239156 -4	112010003272.6			DE	Battery cell with integrated sensing platform
239156 -5	1202195.2			GB	Battery cell with integrated sensing platform
239302 -1	12/533186	US20110025581		US	Antenna assembly
239302 -3	201080045028.7	CN102549837		CN	Antenna assembly
239302 -4	10727602.4	EP2460223		EP	Antenna assembly
239302 -5	2012-522835			JP	Antenna assembly
239302 -6	2012-7005314			KR	Antenna assembly
239302 -7	891/DELNP/2012			IN	Antenna assembly
240804 -2	PI1005763-3	BR1005763		BR	Snap-fit sensor assembly
240804 -3	201010624661.3	CN102183271		CN	Snap-fit sensor assembly
240804 -4	10195952.6	EP2341321		EP	Snap-fit sensor assembly
240923 -1	12/845854	2012-0024876		US	Sealed enclosure and system
240923 -2	201110224491.4	102421265		CN	Sealed enclosure and system
240923 -3	102011052160.7	102011052160		DE	Sealed enclosure and system
240923 -4	2011-163775			JP	Sealed enclosure and system
241065 -3	201080053943.0	CN102667089		CN	Method and system for compensating for variation in attenuation measurements caused by changes in ambient temperature
241065 -4	10752655.0	EP2483538		EP	Method and system for compensating for variation in attenuation measurements caused by changes in ambient temperature
241065 -5	2741/DELNP/2012			IN	Method and system for compensating for variation in attenuation measurements caused by changes in ambient temperature
241230 -3	201010624375.7	CN102157679		CN	Method for fabricating a microelectromechanical sensor with a piezoresistive type readout
241230 -5	2010-289963			JP	Method for fabricating a microelectromechanical sensor with a piezoresistive type readout
241351 -12	201104249-6	177086		SG	Sensor and method for fabricating the same
241351 -3	201110175536.3	102285632		CN	Sensor and method for fabricating the same
241351 -4	102011050837.6	102011050837		DE	Sensor and method for fabricating the same
241351 -6	2011-131721			JP	Sensor and method for fabricating the same

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					same
241351 -7	201104251-2	177087		SG	Sensor and method for fabricating the same
241351 -8	201110175619.2	102313621		CN	Sensor and method for fabricating the same
241351 -9	102011050839.2	102011050839		DE	Sensor and method for fabricating the same
242894 -2	201110463073.0	102583232		CN	Method for fabricating a sensor
242894 -3	102011056484.5			DE	Method for fabricating a sensor
242894 -4	2011/0548			IE	Method for fabricating a sensor
242894 -5	2011-273829			JP	Method for fabricating a sensor
242894 -6	2011-0135385			KR	Method for fabricating a sensor
243599 -1	13/113131	2012-0297884-A1		US	Device for measuring environmental forces and method of fabricating the same
243599 -2	2777309			CA	Device for measuring environmental forces and method of fabricating the same
243599 -3	201210161647.3	102795590		CN	Device for measuring environmental forces and method of fabricating the same
243599 -4	12168716.4	2527810		EP	Device for measuring environmental forces and method of fabricating the same
243599 -5	2012-115672			JP	Device for measuring environmental forces and method of fabricating the same
243599 -6	101118426	201302598		TW	Device for measuring environmental forces and method of fabricating the same
243599 -7	1201201431			VN	Device for measuring environmental forces and method of fabricating the same
243701 -1	13/111619	US2012-0292770		US	Method and device for preventing corrosion on sensors
243701 -2	2777575			CA	Method and device for preventing corrosion on sensors
243701 -3	201210157589.7	CN102786027		CN	Method and device for preventing corrosion on sensors
243701 -4	12168498.9			EP	Method and device for preventing corrosion on sensors
243701 -5	2012-113925			JP	Method and device for preventing corrosion on sensors
243701 -6	101117879	TW201306116		TW	Method and device for preventing corrosion on sensors
243701 -7	1-2012-01379			VN	Method and device for preventing corrosion on sensors
244122 -1	13/032038	2012-0215133		US	Catheter tip device and method for manufacturing same
244122 -2	201210052790.9	102649001		CN	Catheter tip device and method for manufacturing same

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244122 - 3	102012101374.8	102012101374		DE	Catheter tip device and method for manufacturing same
244122 - 4	2012-033481			JP	Catheter tip device and method for manufacturing same
244122 - 5	201200975-9	183628		SG	Catheter tip device and method for manufacturing same
244283 - 1	13/028300	2012-0206316		US	Antenna seal assembly and method of making the same
245124 - 1	13/163203	2012-0320945-A1		US	Robust media sealing temperature probe
245281 - 3	11799903.7			EP	Sensing device comprising a bonding element
245281	20118006566.X	CN 103314284		CN	Sensing device comprising a bonding element
245281	10-2013-7013017	KR 2013-0072262		KR	Sensing device comprising a bonding element
245281	JP App. 2013-540111	JP 2013-543136		JP	Device for measuring properties of working fluids
246128 - 1	13/167217	2012-0325513-A1		US	Connector assembly having strain relief feature
247491 - 1	13/182609			US	Heating system, heater, and methods of heating a component
247491 - 2	BR102012017383-2			BR	Heating system, heater, and methods of heating a component
247491 - 3	201210241935.X	102883478		CN	Heating system, heater, and methods of heating a component
247491 - 4	12175803.1			EP	Heating system, heater, and methods of heating a component
247491 - 5	2012-156068			JP	Heating system, heater, and methods of heating a component
247604 - 1	13/222434		8561320	US	System and method for determining status of a drying cycle and for controlling a dryer
248214 - 1	13/215393	20130049232		US	Component assembly using a temporary attach material
248214 - 2	PCT/US13/27594			WO	Component assembly using a temporary attach material
248214 - 3	102106779			TW	Component assembly using a temporary attach material
248451 - 2	201210161077.8	102778248		CN	Apparatus and method to attach probe to junction box
248451 - 3	102012104105.9	102012104105		DE	Apparatus and method to attach probe to junction box
250172 - 1	13/659443			US	Device and method for measuring moisture content
250172 - 3	102013111131.9			DE	Device and method for measuring moisture content
250172 - 4	2013-219909			JP	Device and method for measuring moisture content
250172 - 5	2013/0309			IE	Device and method for measuring moisture content

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250212 - 1	13/406395			US	Catheter die and method of fabricating the same
250212 - 2	PCT/US13/27608			WO	Catheter die and method of fabricating the same
250212 - 3	102107074			TW	Catheter die and method of fabricating the same
250216 - 1	13/436185	20130259964		US	Catheter die
250450 - 1	13/298271			US	System and method for upgrading firmware
251309 - 1	13/164828	US-2012-0330596		US	Self-calibrating sensor, system, and computer program product
251309 - 2	US12/42856	WO2012177528		WO	Self-calibrating sensor, system, and computer program product
252202 - 1	13/307834			US	Pressure sensor assembly
252202 - 2	102012111597.4			DE	Pressure sensor assembly
252202 - 3	201210501256.1			CN	Pressure sensor assembly
252202 - 4	2012-258069			JP	Pressure sensor assembly
252202 - 5	1201005860			TH	Pressure sensor assembly
252335 - 1	13/567723			US	Device for measuring forces and method of making the same
252335 - 2	201310338471.9			CN	Device for measuring forces and method of making the same
252335 - 5	13178458.9			EP	Device for measuring forces and method of making the same
252347 - 1	13/443029	20130263671		US	Fluid pressure spike attenuation feature for pressure sensing devices
252347 - 2	US13/33202			WO	Fluid pressure spike attenuation feature for pressure sensing devices
252815 - 1	13/343116			US	Ceramic heating device
252815 - 2	2800055			CA	Ceramic heating device
252815 - 3	12199342.2			EP	Ceramic heating device
253358 - 1	13/538146			US	Pressure sensor assembly
253358 - 2	PCT/US13/45086			WO	Pressure sensor assembly
256203 - 1	13/410857			US	Flexible cable for low profile electrical device
256203 - 2	PCT/US13/27438			WO	Flexible cable for low profile electrical device
256203 - 3	102107395			TW	Flexible cable for low profile electrical device
256340 - 1	13/323369			US	Method and device for determining a comparative moisture level

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256738 - 1	13/368081			US	Method and apparatus for displaying the temperature of an object
257869 - 1	13/495716			US	Sensor assembly with protective coating and method of applying same
257869 - 2	13171733.2			EP	Sensor assembly with protective coating and method of applying same
257869 - 3	201310232936.2			CN	Sensor assembly with protective coating and method of applying same
257869 - 4	2013-121393			JP	Sensor assembly with protective coating and method of applying same
257869 - 5	2013-0067359			KR	Sensor assembly with protective coating and method of applying same
260006 -1	13/485526			US	Fine-pitch flexible wiring
260006 -2	PCT/US13/41750			WO	Fine-pitch flexible wiring
260610 - 1	13/685982			US	Thermistor and method of constructing a thermistor
261568 - 1	13/526589			US	Non-dispersive infrared sensor with a reflective diffuser
261568 - 2	2818156			CA	Non-dispersive infrared sensor with a reflective diffuser
261568 - 3	201310242739.9			CN	Non-dispersive infrared sensor with a reflective diffuser
261568 - 4	13172490.8			EP	Non-dispersive infrared sensor with a reflective diffuser
261568 - 5	0			HK	Non-dispersive infrared sensor with a reflective diffuser
261568 - 6	1566/DEL/2013			IN	Non-dispersive infrared sensor with a reflective diffuser
261568 - 7	2013-125112			JP	Non-dispersive infrared sensor with a reflective diffuser
261568 - 8	2013-0069685			KR	Non-dispersive infrared sensor with a reflective diffuser
261568 - 9	20135628			FI	Non-dispersive infrared sensor with a reflective diffuser
262124 - 1	13/679144			US	Fluid level sensor system and method
263984 - 1	13/652764			US	Sensor attachment method incorporating locking retention feature that will only engage when the device is properly installed
263984 - 2	PCT/US13/65140			WO	Sensor attachment method incorporating locking retention feature that will only engage when the device is properly installed
264005 - 1	13/834138			US	Moisture meter
265358 -1	13/801201			US	Systems and methods for acoustic detection using flow sensors
265502 -1	61/798771			US	Systems and methods for hybrid flow sensing

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265502 -2	13/969041			US	Systems and methods for hybrid flow sensing
265545 -1	13/834453			US	Concrete structure moisture measurement system
265647 -1	13/773,004			US	Sensor and method of making a sensor
268951 -1	14/072,234			US	Systems and methods for temperature compensated flow sensing
269122 -1	14/072,393			US	Systems and methods for flow sensing in a conduit

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138981 -24	2001-7002836			KR	Proportional micromechanical device
185518 -3	01991579.2			EP	Method of compensating for drift in gas sensing equipment
185522 -8	01101108.6			HK	Diffusion-type NDIR gas analyzer with improved response time due to convection flow
192974 -2	07101619.0	1816486		EP	Methods and systems for detecting proximity of an object
192974 -3	2007-023769			JP	Methods and systems for detecting proximity of an object
192976 -2	07101644	1816455		EP	Methods and systems for determining temperature of an object
233093 -1	8164833.9	2166330		EP	Miniature pressure transducer
238009 -3	1120120026860			BR	Thermal sensor device and method of assembly
238009 -4	201080045691.7	102549403		CN	Thermal sensor device and method of assembly
238009 -5	10737401.9	2462417		EP	Thermal sensor device and method of assembly
238009 -6	2012-523625			JP	Thermal sensor device and method of assembly
181222 -5	06800501.6	1935039		EP	Mid-infrared resonant cavity light emitting diodes
181222 -6	1103/DELNP/2008			IN	Mid-infrared resonant cavity light emitting diodes
185522 -7	2307782			CA	Diffusion-type NDIR gas analyzer with improved response time due to convection flow